



**The US Particle Accelerator School  
Titanium Sublimation Pumps**

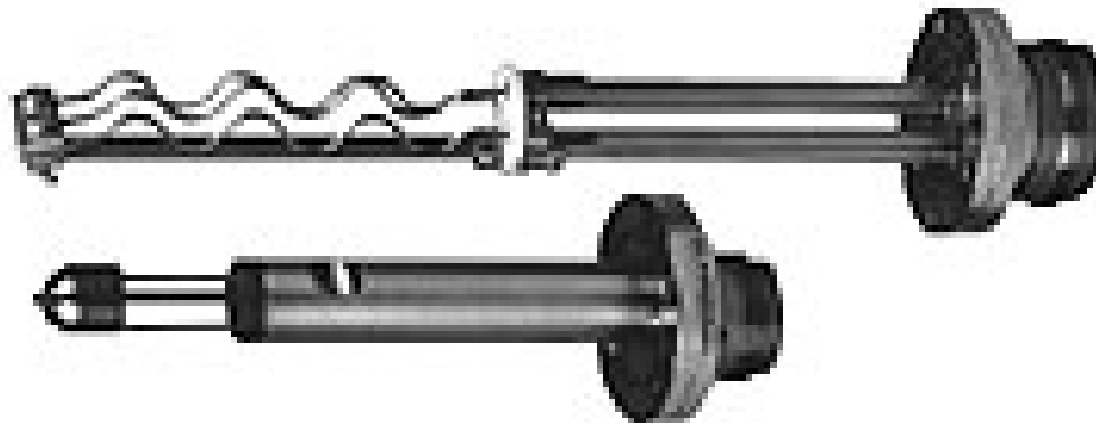
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Lawrence Livermore National Laboratory  
June 10-14, 2002**



## Titanium Sublimation Pumping (TSP)

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- Gases are pumped by “gettering.” “Getterable” gases are pumped at high speeds by chemisorption.
- TSP is very practical and a cost effective mechanism.
- Manufacturers don't sell TSPs; they sell Titanium sources.





# Titanium Sublimation Pumping

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- “Sticking Coefficients” of gases are important in understanding TSPs.
- Sticking coefficient ( $\alpha$ ), is the probability that a specific gas molecule, when striking a surface will permanently stick.

$$v = 3.5 \times 10^{22} \frac{P}{\sqrt{MT}} \quad \text{Impingement rate}$$



## Titanium Sublimation Pumping

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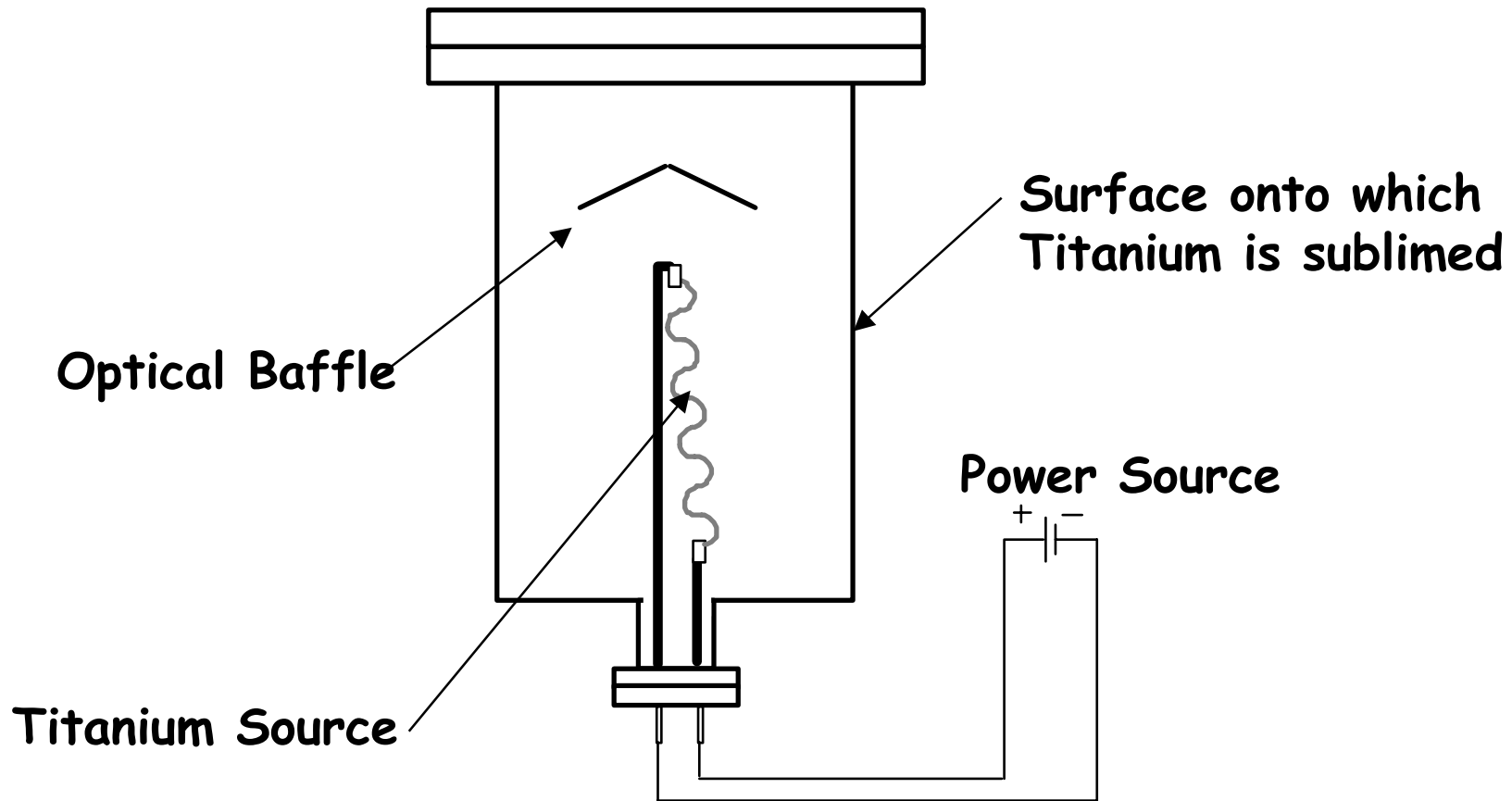
- TSPs are “surface” pumps that are surface conductance limited.
- There is a relationship between the number of active metal energy sites per unit area and the sticking coefficient.
- The sticking coefficient will decrease as the active metal energy sites decrease.

Maintaining a balance between the incident flux of gas and the available chemisorption sites is key to Titanium Sublimation Pumping.



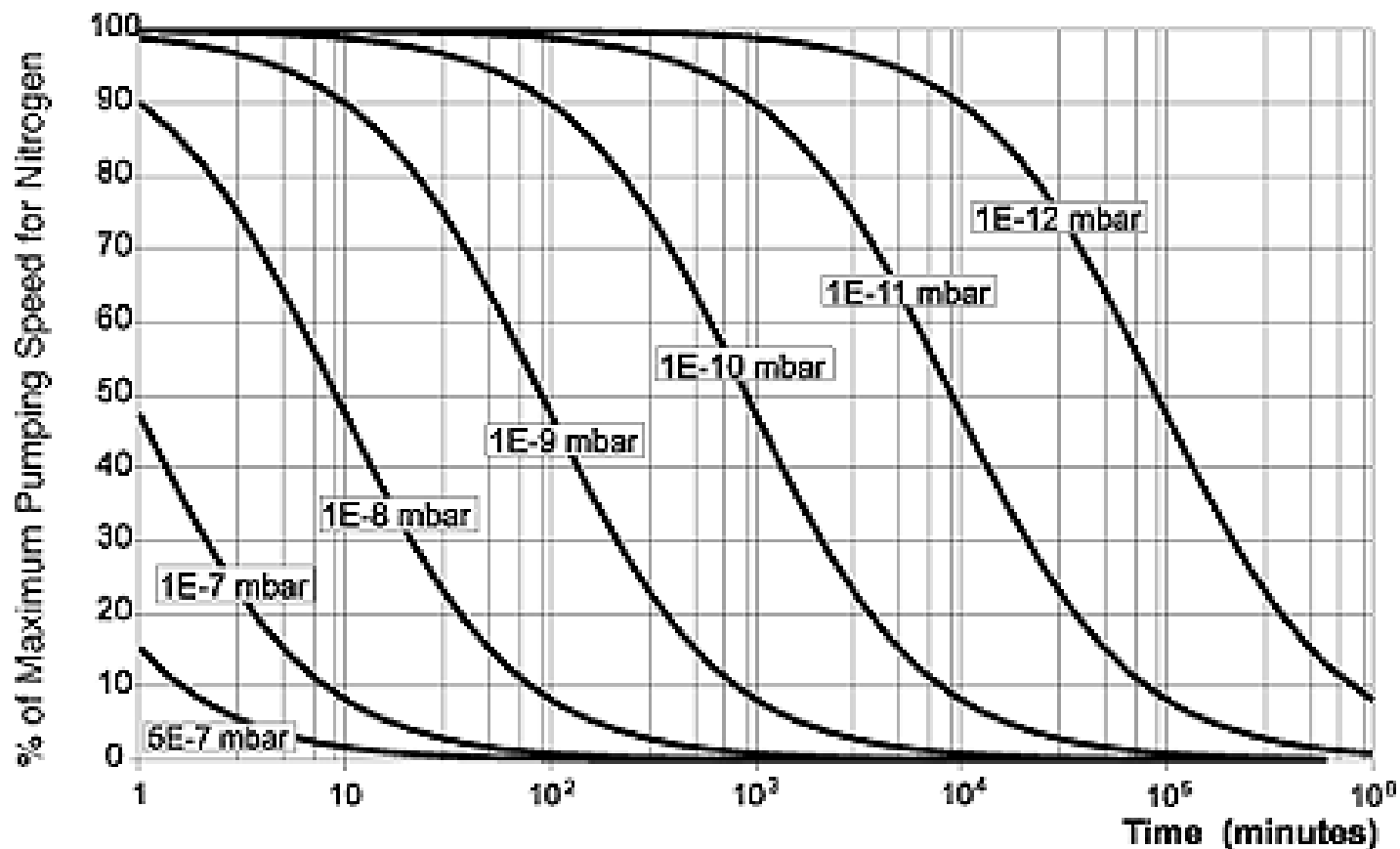
# Features of a Titanium Sublimation Pump

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# TSP vs. time (at various pressures)



Ref. Varian Vacuum



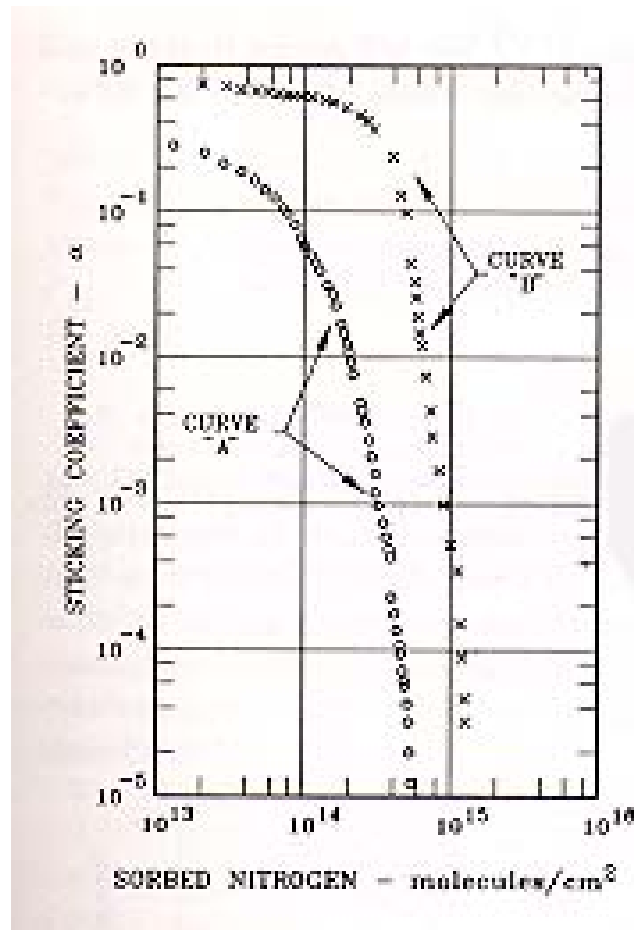
# Sublimation Processes

1. **Batch sublimation** - periodic sublimation of titanium onto the pumping surface. The titanium film is then allowed to saturate with gas over time.

Curve A - batch layer of  $8.0 \times 10^{14}$  Ti atoms/cm<sup>2</sup> deposited on a previously exposed base of  $1.7 \times 10^{17}$  atoms/cm<sup>2</sup>

Curve B - batch layer of  $8.3 \times 10^{14}$  Ti atoms/cm<sup>2</sup> deposited on a previously exposed base of  $1.0 \times 10^{18}$  atoms/cm<sup>2</sup>

(Ref. "Sorption of Nitrogen by Titanium Films," Harra and Hayward, Proc. Int. Symp. On Residual Gases in Electron Tubes, 1967)





## Sublimation Processes

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2. **Continuous Sublimation** - titanium sublimation onto a pumping surface at a constant and continuous rate. Pumping sites are replenished at a rate equal to the rate at which they are occupied.

$$S_s = \alpha_i C_i A_c$$

where  $S_s$  = surface pump speed

$\alpha_i$  = sticking coefficient for gas species "i"

$C_i$  = aperture conductance per  $\text{cm}^2$  for gas species "i"

$A_c$  = total pumping surface area





# Factors that Influence Sticking Coefficient

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- Thickness of Titanium film
- Ratio of pumping speed to Titanium sublimation rate
- Surface temperature at the time of sublimation
- Surface temperature at the time of gas sorption
- Film deposition process (batch or continuous)
- Gas species
- Gas desorption and synthesis at Titanium source
- Partial pressures of gases at time of sublimation
- Contamination of film by some gas
- Effects of film annealing
- Variations of surface and bulk diffusion processes

Some have proposed that there is a “pecking order” of gases pumping by Titanium chemisorption



Pumped Gas	Displaced Gas				
	CH <sub>4</sub>	N <sub>2</sub>	H <sub>2</sub>	CO	O <sub>2</sub>
CH <sub>4</sub>		no	no	no	no
N <sub>2</sub>	yes		no	no	no
H <sub>2</sub>	yes	yes		no	no
CO	yes	yes	yes		no
O <sub>2</sub>	yes	yes	yes	yes	
$\alpha_m$	$< 10^{-3}$	0.3	0.05	0.85	0.95

This is controversial and probably only true for CH<sub>4</sub> and H<sub>2</sub>.



# Typical Engineering Values for TSP

Test Gas	Max. Sticking Coefficient- $\alpha_m$		Max. Speed <sup>a</sup> (liters/sec-cm <sup>2</sup> )		Max. Capacity of Film- $\times 10^{15}$ (molecules/cm <sup>2</sup> ) <sup>b</sup>	
	300 K	77 K	300 K	77 K	300 K	77 K
H <sub>2</sub>	0.06	0.4	2.6	17	8-230 <sup>c</sup>	7-70
D <sub>2</sub>	0.1	0.2	3.1	6.2	6-11	-
H <sub>2</sub> O	0.5	-	7.3	14.6	30	-
CO	0.7	0.95	8.2	11	5-23	50-160
N <sub>2</sub>	0.3	0.7	3.5	8.2	0.3-12	3-60
O <sub>2</sub>	0.8	1.0	8.7	11	24	-
CO <sub>2</sub>	0.5	-	4.7	9.3	4-12	-

a) Speed calculated at RT

b) Wide variations due to film roughness

c) Wide variations due to bulk diffusion into film

(Ref. "Sorption of Nitrogen by Titanium Films," Harra and Hayward, Proc. Int. Symp. On Residual Gases in Electron Tubes, 1967)



# Titanium Sublimation Sources

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There are three types of sources for sublimating Titanium on pumping surfaces:

1. Filamentary sources
2. Radiantly heated sources
3. Electron-gun sources



# Titanium Filamentary Sources

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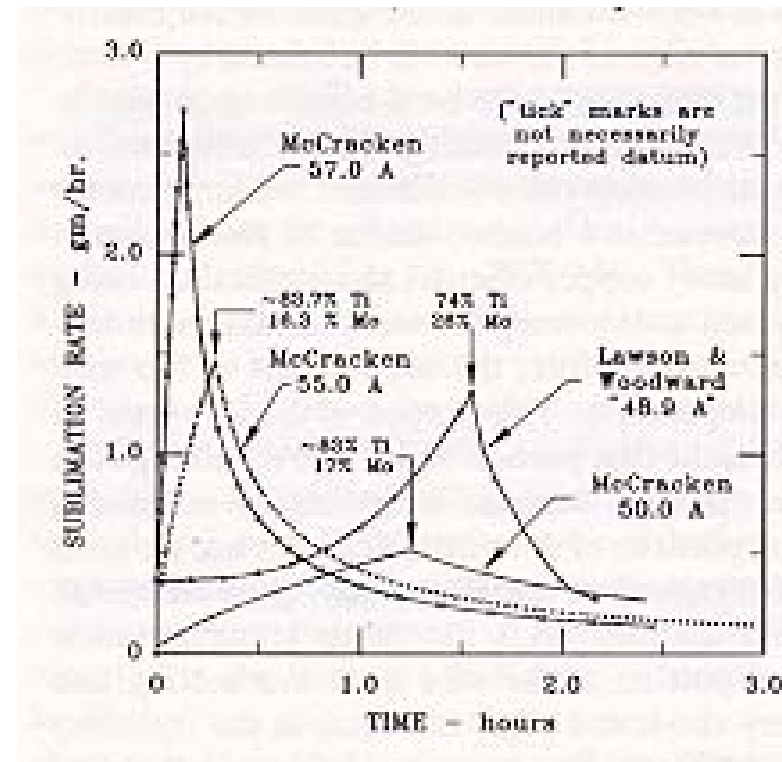
- Titanium has poor mechanical strength at sublimation temperatures.
- Titanium filaments must be coupled with other materials for mechanical strength.
  - One method is to wrap the Titanium filaments on a structural member (Ta or W)
  - The most prevalent solution is to alloy Titanium with Molybdenum (85% Ti; 15% Mo by weight)





# Constant current operation of TSPs

- Constant current operation of Titanium filaments produces increases in sublimation rates early in the life of the filament.
- This is probably due to the progressively leaner mixture of Titanium in the filaments.
- Filaments develop rougher surface textures as the mixture changes.
- Rough texture = greater surface area = higher emissivity = lower operating temperature = lower sublimation rates.



Ref. "Properties of Titanium-Molybdenum Alloy Wire as a Source of Titanium for Sublimation Pumps," Lawson and Woodward, *Vacuum* **17**, 205 (1967)

"Titanium Filaments for Sublimation Pumps" McCracken and Pashley, *JVST*, **3**, 96 (1966)



# Constant Voltage Operation of TSP Filaments

- Constant voltage operation is rarely done.
- Constant voltage operation in conjunction with RT cycling produces more predictable sublimation rates

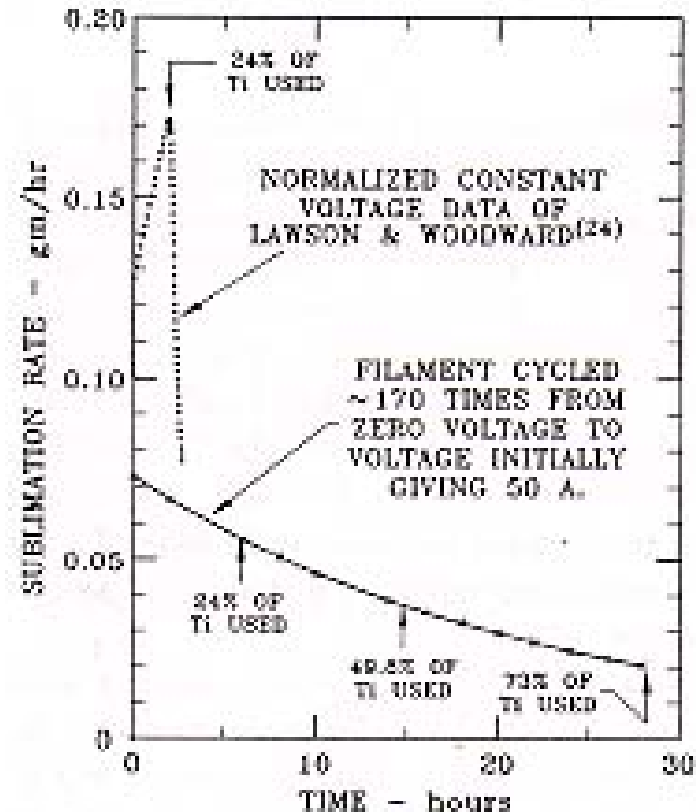
$$R(t) = R_0 e^{-at}$$

where  $R_0$  = initial sublimation rate

$a$  = constant

$t$  = cumulative sublimation time

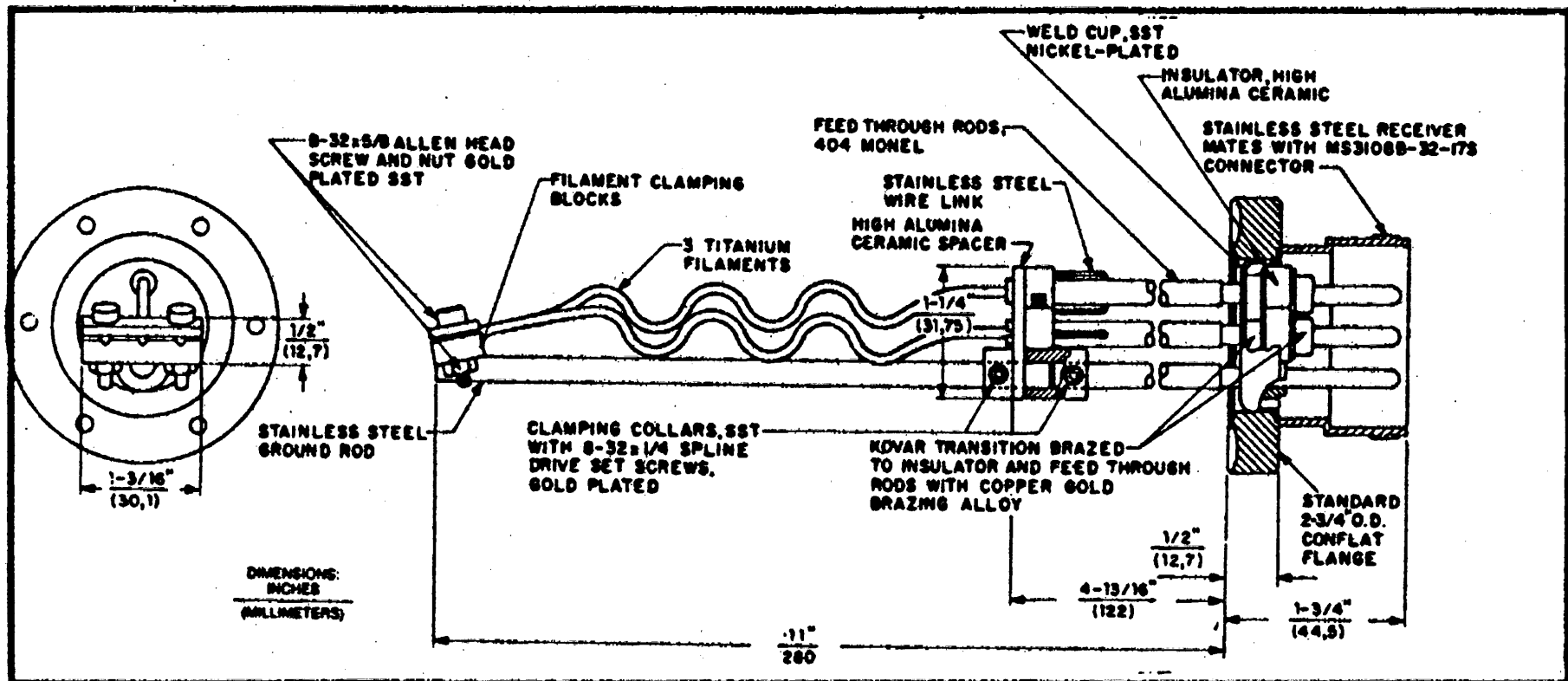
- Titanium sublimation rates are dependent on Ti and Mo proportions and the number of temperature cycles through the crystallographic transformation temperature.



Ref. "Properties of Titanium-Molybdenum Alloy Wire as a Source of Titanium for Sublimation Pumps," Lawson and Woodward, *Vacuum* **17**, 205 (1967)



# Titanium Sublimation Cartridge

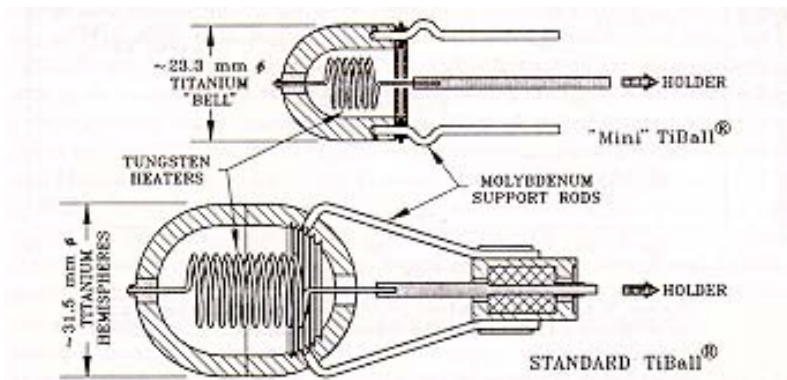




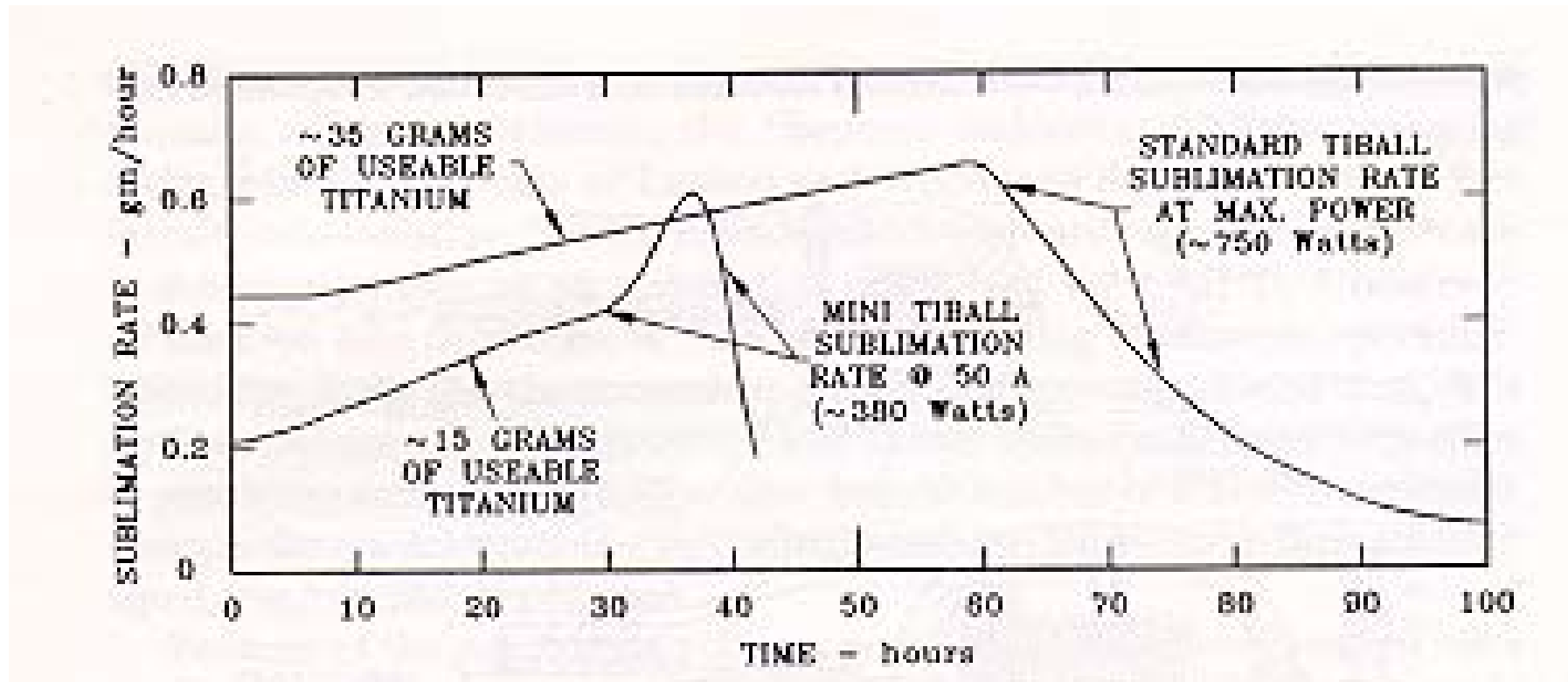


# Radiantly Heated Titanium Sources

- Titanium heating occurs primarily through radiation from a secondary Tungsten (W) filament.
- The Titanium sphere surrounds the filament and provides the return current path.
- Titanium source assembly is mounted as a removable flange with an electrical feedthrough.
- Functional life ends when a "hole" opens up in the Titanium sphere.



# Sublimation rates for Varian TiBall and "Mini" TiBall Sources



Ref. "A Radiant Heated Titanium Sublimator," Proc. 5th Int. Vacuum Congress, 1971, JVST 9 (1), 552 (1972)

# Disadvantage of Radiantly Heated Sources

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- Sources require operation at some level of standby power to maintain Titanium temperature above  $900^{\circ}\text{C}$ .
- Temperature cycling through the crystallographic phase transformational temperature of  $880^{\circ}\text{C}$  eventually results in distortion.
- Two things can happen (both bad):
  1. Distortion leads to electrical shorting of W filament.
  2. Distortion leads to increased emissivity, lower temperatures, and reduced sublimation rates.

# Summary of Radiantly Heated Titanium Sources

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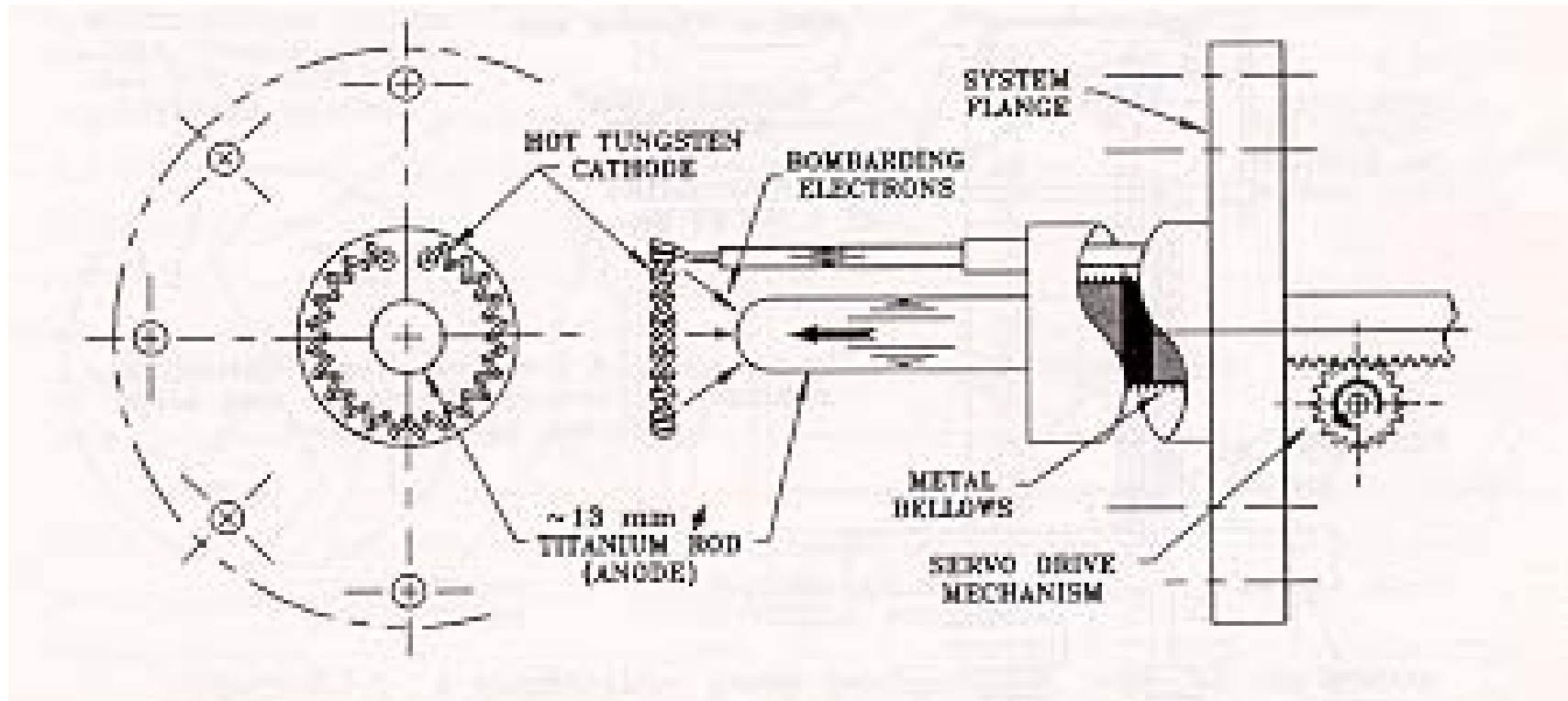


- Standby power (100-200 W) required to prolong source life.
- Heat from standby mode can increase gas load.
- In storage rings (operating at  $10^{-10}$  Torr), Titanium quantity is less important than reliability.





# Electron-gun Titanium Sources



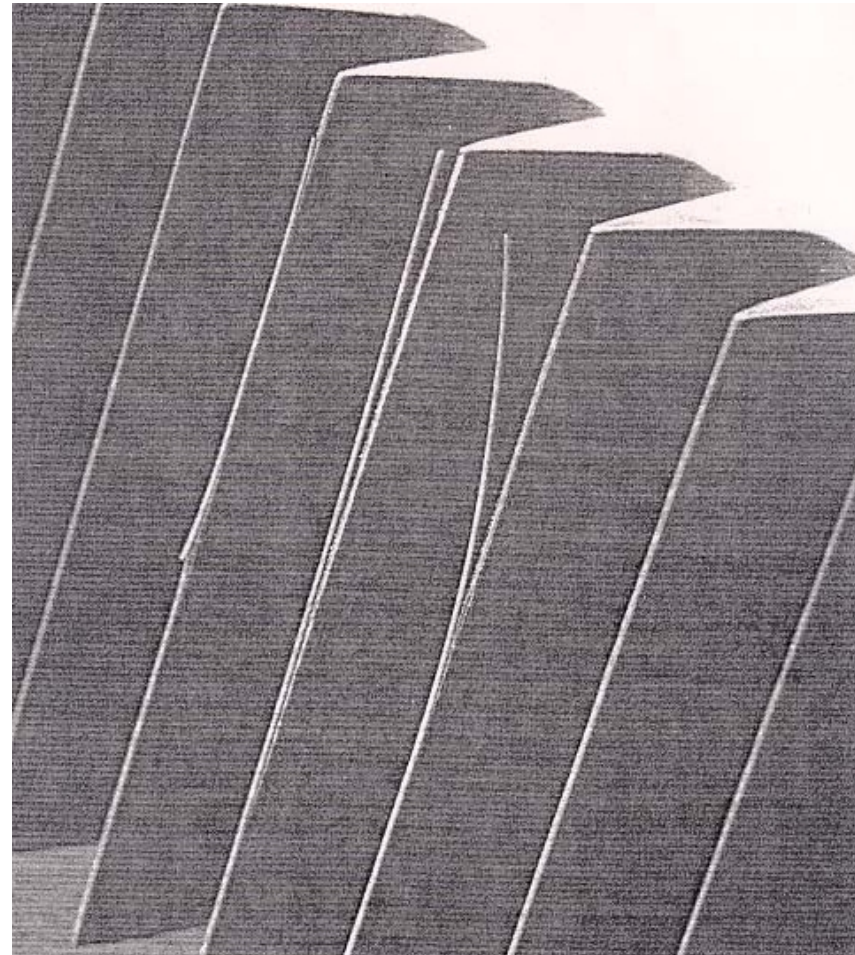
Ref. Perkin-Elmer Corporation



# Peeling of Titanium Films

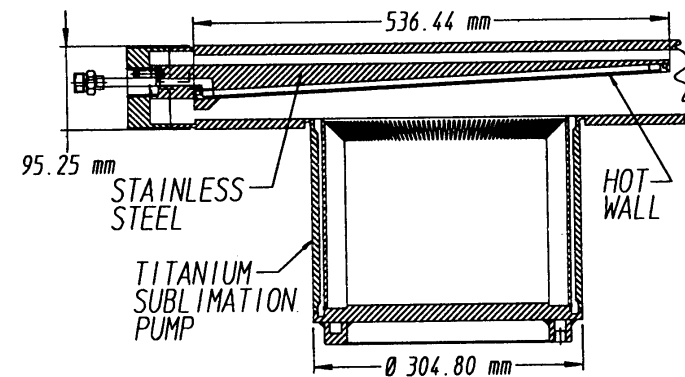
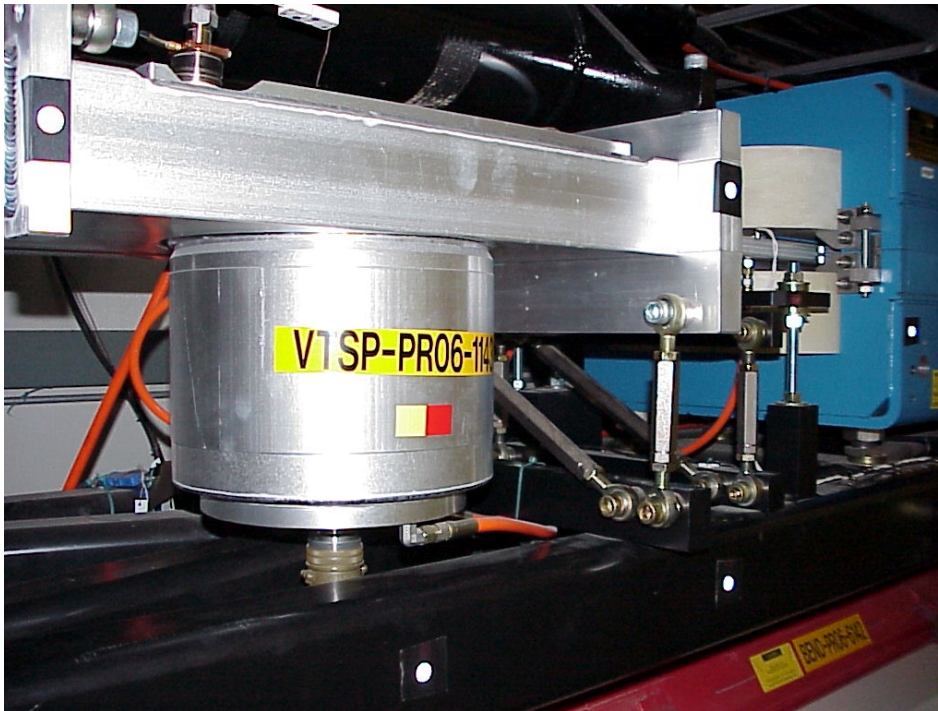
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- As Titanium builds-up on a pumping surface, it will begin to peel.
- A typical thickness where peeling begins is 0.05 mm.
- Peeling produces dust particles and increases surface temperatures during sublimation.
- Because of peeling, pumping surfaces may require periodic cleaning (glass bead blasting and/or chemical cleaning).
- If peeling is a problem, a TSP was probably a bad choice or you are misusing the pumps.

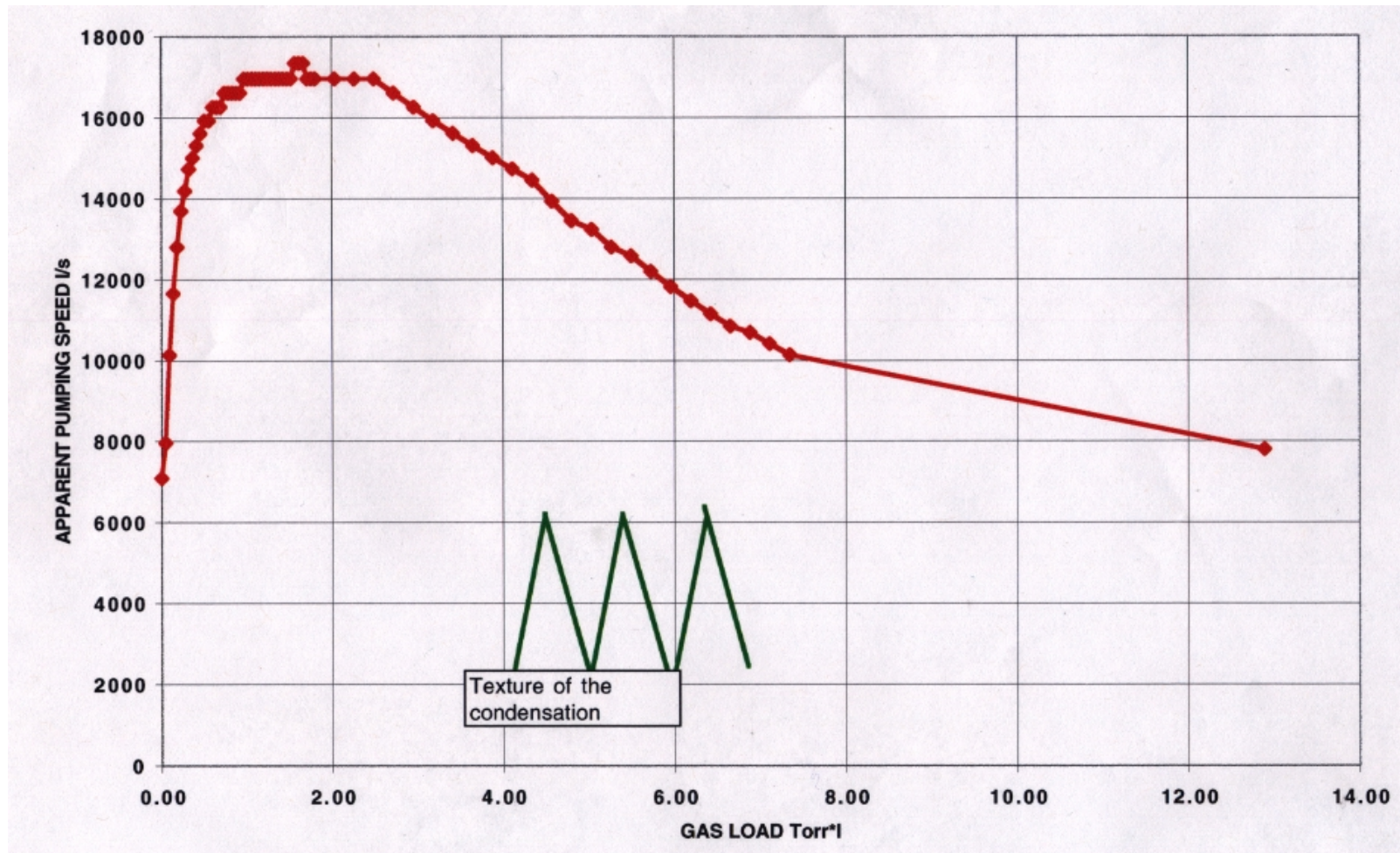




# PEP-II LER Arc TSP and Photon Stop



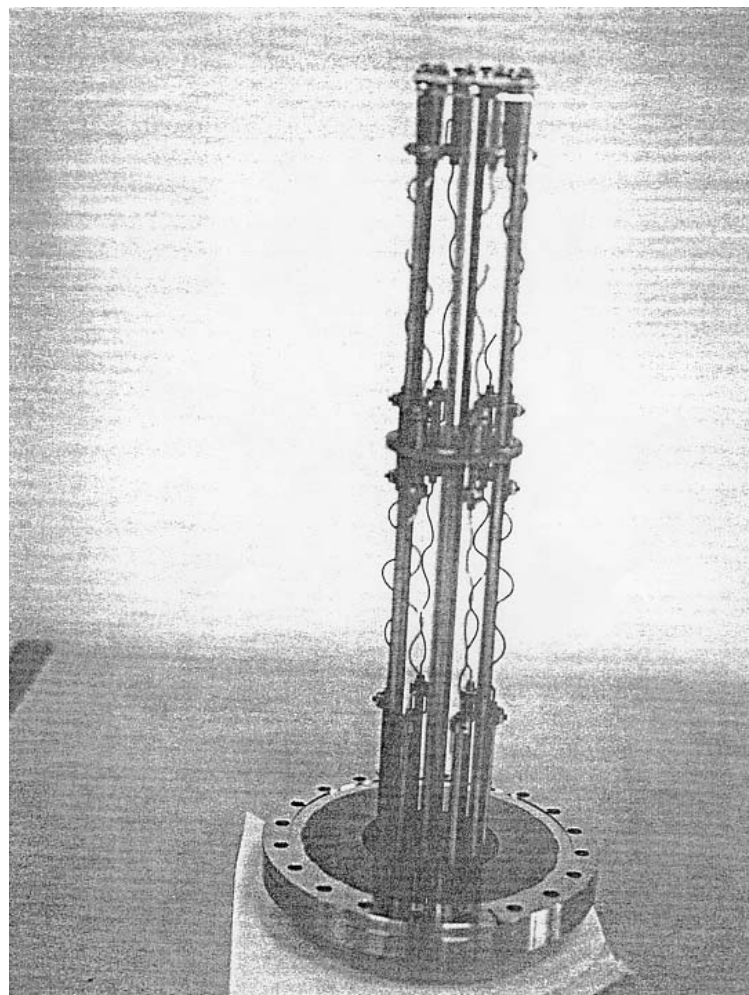
# Pumping Speed as a Function of Gas for an Extended Surface 6" TSP PUMP



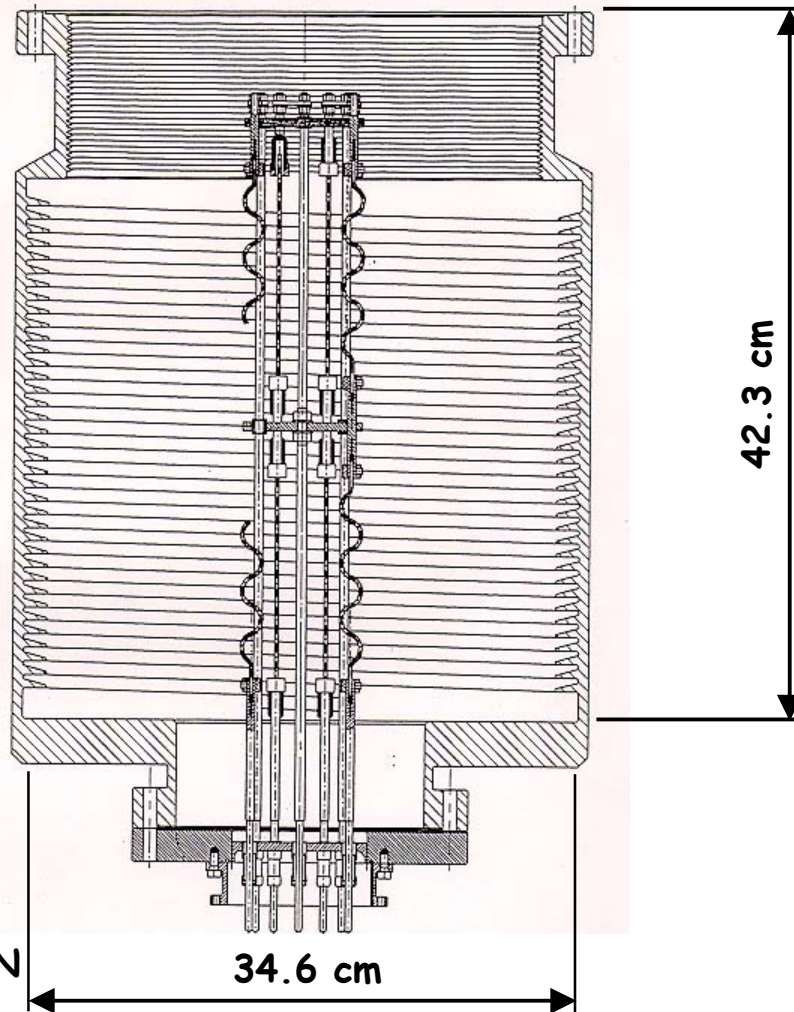


# Photo of custom Varian TSP designed for ALS and DAFNE

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# DAFNE Collider TSP



Courtesy: C. Vaccarezza, INFN